

Electronic Patent Application Fee Transmittal

Application Number:	09546174
Filing Date:	11-Apr-2000
Title of Invention:	HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS
First Named Inventor/Applicant Name:	Chih-Chien Liu
Filer:	William H. Wright
Attorney Docket Number:	JIA 462C1

Filed as Large Entity

Utility Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

Post-Allowance-and-Post-Issuance:

Extension-of-Time:

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Submission- Information Disclosure Stmt	1806	1	180	180
Total in USD (\$)				180